New Product

C & D SEMICONDUCTOR SERVICES, INC.

V1020 Microscope Wafer Loader

Description

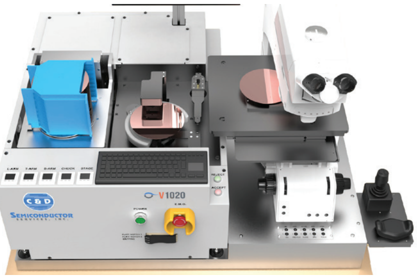
The next generation V1020 Microscope Wafer Loader achieves higher throughput than the previous generation while maintaining C&D's well-known standards of reliability and ease of use. The V1020 is designed to fully automate loading and unloading of wafers from cassette to the microscope stage for inspection. Along with being faster, the new generation V1020 comes with improved inspection features.

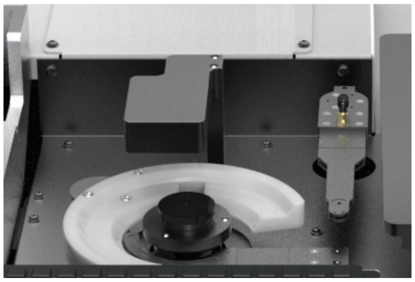
Features

- Wafer size: 50 mm to 200 mm
- Auto size detection for up to two wafer sizes
- One cassette for loading and unloading (SMIF loading optional)
- Cassette mapping
- Microscope inspection on XY stage with 360 degree rotation vacuum chuck
- Compatible with most microscopes
- User friendly interface
- Ergonomic cassette loading
- Configurable speedhandle
- CE Certified
- SECS/GEM compliant

New & Improved Features

- Greater than 200 wafers per hour throughput
- An intermediate station for wafer centering, macro inspection, and orientation flat/notch alignment
- Dual arm robot for fast wafer exchange
- Motorized stage
- Top and backside macro inspection
- Bright light inspection
- OCR capability





Faster Wafer Exchange

The new intermediate station is where wafer centering, macro and bright light inspection, orientation notch and flat alignment are performed. While the operator performs microscope inspection on wafer, the next wafer is prepared in the intermediate station. As soon as the operator finishes inspection of the current wafer, the dual arm robot immediately transfers the new wafer and removes the current wafer, eliminating the wait period of previous generation. The dual arm robot allows for fast transfer between stations.

Ergonomic Design

The ergonomic cassette loading option puts the cassette platform into a tilted position for loading and unloading the cassette. This reduces considerable stress on the wrists and hands of users.

The Loader is fitted with a user programmable and ergonomic speedhandle. The five-button speedhandle fits to the microscope stage and is used by the operator to navigate the XY stage during manual wafer inspection. The buttons are programmable within the V1020 software.


Microscope Loader V1020

Connected
Counter: 9999

1:24 AM
6/28/2014

Linear Arm: ARM HOME OK

RECIPE: COMP

Total 15

STAGE OUT

25	
24	
23	
22	
21	
20	
19	
18	
17	
16	
15	
14	
13	
12	
11	
10	
9	
8	Present
7	Present
6	Present
5	Present
4	Present
3	Present
2	Processing...
1	Processing...

Powerful software allows for easy and flexible inspection

C&D Microscope Wafer Loader has always been known for its ease of use and flexibility. Wafers can easily be selected for inspection and re-inspection. The user interface is designed so that operators use the Loader through engineer developed recipes. A recipe typically takes seconds to create and save. A recipe includes wafer select, inspection angle, return angle, flat and notch alignment, wafer rotation speed, and wafer direction.

Technical Data

Interface	Touchscreen PC based software user interface
Dimensions	38" x 30"
Facility Requirements	Vacuum: 25" / 600 Hg

Footprint